

## **Fabrication of Cu<sub>2</sub>O homojunction with ZnO buffer layer**

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### **ABSTRACT**

Development of cost effective and efficient solar cells is a priority in studies of renewable energy. Cu<sub>2</sub>O comes with a promising photon to electron conversion efficiency of 20% with high absorbance properties as well as non-toxicity. Overall efficiency of Cu<sub>2</sub>O based solar cells has been kept quite low compared to the theoretical limit due to the low fill factor and the open circuit voltage of Cu<sub>2</sub>O homojunction devices. In this study, a thin layer of ZnO have been deposited in between n-Cu<sub>2</sub>O and p-Cu<sub>2</sub>O with the expectation of improving the V<sub>oc</sub> value and the fill factor by acting as a buffer layer which blocks the current flow from n-Cu<sub>2</sub>O to p-Cu<sub>2</sub>O in operation. Growth of n-type and p-type Cu<sub>2</sub>O were carried out by electrodeposition using previously optimized conditions in acetate and lactate baths respectively. Growth of ZnO was done by spin coating using a solution prepared by dissolving zinc acetate dihydrate in methanol. Formation of ZnO on Cu<sub>2</sub>O by spin coating technique has been confirmed by HEXRD. The best n-Cu<sub>2</sub>O/ZnO/p-Cu<sub>2</sub>O device produced V<sub>oc</sub> of 438 mV, J<sub>sc</sub> of 8.37 mAcm<sup>-2</sup>, FF of 34.9% and η of 1.28%.

Keywords: Cu<sub>2</sub>O electrodeposition, ZnO, Buffer layer, ZnO spin-coating.

### **1. INTRODUCTION**

Cuprous Oxide (Cu<sub>2</sub>O) is a low-cost semiconductor material which can be used to fabricate solar cells with efficiencies up to 20%. Having a ~ 2 eV direct bandgap allows Cu<sub>2</sub>O to capture the high intensity region of the solar spectrum resulting in high efficiency. Other than combining Cu<sub>2</sub>O with another material to form a heterojunction, homojunction solar cells are expected to be more suitable and cost effective [1] [2]. It is reported that the conductivity type of cuprous oxide can be controlled by varying the deposition parameters by electrodeposition technique. To date, the maximum reported efficiency of Cu<sub>2</sub>O homojunction solar cells is around 2% which is quite low compared to the theoretical limit. The reason behind this problem is due to the low open circuit voltage followed by low fill factor (FF) (<30%).

Presence of surface states, inherent p-type conductivity of n-Cu<sub>2</sub>O, recombination rate are the factors that should be carefully controlled in order to achieve higher V<sub>oc</sub> values. However, applications or growth of n-Cu<sub>2</sub>O is not commonly reported compared to p-Cu<sub>2</sub>O in the literature. Therefore, investigations have to be done on perfecting n-Cu<sub>2</sub>O thin films to be used in solar cells. In our previous reports, improving the n-type conductivity and eliminating the surface states and fermi level pinning of n-Cu<sub>2</sub>O have been investigated [3]. n-Cu<sub>2</sub>O was grown on Ti substrates and mitigation of p-type

conductivity was observed with annealing treatments. p-type conductivity of n-Cu<sub>2</sub>O thin films were completely eliminated by depositing a thin Cu layer prior to the deposition and annealing at low temperatures for long durations [4]. On the other hand, growth of p-Cu<sub>2</sub>O is commonly reported in the literature using various methods such as thermal evaporation, epitaxial growth, chemical bath deposition, thermal oxidation [5]. Most of the reported homojunction devices were fabricated by using electrodeposition technique since it is the only possibility of growth of n-Cu<sub>2</sub>O. Uniform p-Cu<sub>2</sub>O with high photoresponse were reported by electrodeposition technique in lactate bath in highly alkaline conditions [6].

Fabrication of Cu<sub>2</sub>O homojunction as a p-i-n structure with a wide bandgap layer as the intrinsic, could shift fermi energies of n- and p-Cu<sub>2</sub>O apart while seizing the unwanted recombination at the junction acting as a buffer layer. Wide bandgap materials such as ZnO, TiO<sub>2</sub>, ZnS are commonly reported in literature in heterojunction solar cells as well as organic solar cells [7], [8]. ZnO is a matching buffer layer for Cu<sub>2</sub>O where ZnO/Cu<sub>2</sub>O heterojunctions are reported commonly [9]. However, in order to fabricate Cu<sub>2</sub>O homojunction, the growth of ZnO on top of the n-Cu<sub>2</sub>O is quite challenging and not reported previously by anyone to our knowledge to the date. Electrodeposition of ZnO is generally performed in acidic baths [10],[11] in which Cu<sub>2</sub>O gets easily dissolved. Similar scenario applies to chemical bath depositions [12]. On the other hand, it is require high temperature annealing to form ZnO which cannot be applied with n-Cu<sub>2</sub>O because n-type conductivity of Cu<sub>2</sub>O will be hindered by annealing at temperatures beyond 200 °C [13] and Cu<sub>2</sub>O get oxidized and form CuO at temperatures higher than 400 °C [14]. Therefore, in this study, the possibility of growth of ZnO thin films on n-Cu<sub>2</sub>O thin film were explored without damaging n-Cu<sub>2</sub>O thin film by spin coating technique [15] and thereby fabrication of Cu<sub>2</sub>O homojunction. Since the thickness of the ZnO layer plays a key role in this proposed device, it has to be optimized by changing the rpm as well as the solution concentration.

## **2. EXPERIMENTS AND METHODS**

### **2.1 n-Cu<sub>2</sub>O Electrodeposition**

Cu<sub>2</sub>O thin films were grown on Ti substrates by electrodeposition using a Gamry series 300 Potentiostat / Galvanostat ZRA and a three electrode electrochemical cell having Ti substrate as the working electrode, Pt plate as counter electrode and Ag/AgCl electrode as the reference electrode. Prior to the deposition, Ti substrates were polished with p800, p1200 sandpapers, rinsed with detergent and ultrasonicated in HCl for 15 minutes and finally rinsed with D.I. water thoroughly. Deposition bath was a 100 ml aqueous solution containing 0.1 M sodium acetate and 0.01 M cupric acetate and the pH of the bath was adjusted to be 6.1 by adding diluted acetic acid. Electrodeposition was carried out using the above mentioned setup at the deposition potential of -200 mV with respect to the Ag/AgCl reference electrode. Layer thickness was controlled by limiting the deposited charge to 2 coulombs per cm<sup>2</sup> to obtain 1.6 μm thin n-Cu<sub>2</sub>O films. Temperature of the bath was maintained at 55 °C while stirring at 50 rev/min with a magnetic stirrer.

## 2.2 Spin Coating ZnO

ZnO buffer layer was deposited on Ti/n-Cu<sub>2</sub>O electrode by spin coating. Deposition solution was prepared by dissolving 1 g of zinc acetate dihydrate in 10 ml of methanol. Solution was stirred for 1 hour and aged for 24 hours before using. Spin coating was carried out at a spinning speed of 2500 rpm for 10 seconds using an Ossila spin coater. Resulted samples were carefully placed in the Carbolite tube furnace for annealing in air in order to remove acetate complexes to form ZnO. Even though the reduction of zinc acetate is reported at high temperatures (>450 °C), annealing was done at low temperature for a long duration which was 100 °C for 24 hours followed by 150 °C for 30 minutes. These annealing conditions were selected for the formation of ZnO as well as optimization of the n-type response of Cu<sub>2</sub>O layer.

## 2.3 p-Cu<sub>2</sub>O Electrodeposition

p-Cu<sub>2</sub>O thin film was then electrodeposited on annealed samples in a three electrode electrochemical cell containing 0.4 M Copper Sulphate pentahydrate, 4 M Sodium Hydroxide and 2.1 M lactic acid. Deposition potential of -450 mV was applied to Ti /n-Cu<sub>2</sub>O working electrode with respect to the Ag/AgCl reference electrode and deposition charge was limited to 0.1 coulombs per cm<sup>2</sup> in order to maintain the thickness of p-Cu<sub>2</sub>O film at 0.08 μm. Cu<sub>2</sub>O layer thicknesses of the device were selected according to the optimum Ti/n-Cu<sub>2</sub>O/p-Cu<sub>2</sub>O/Au device fabrication conditions which were carried out previously.

## 2.4 Sulphiding

After the deposition, samples were rinsed thoroughly with D.I. water and dried in hot air and exposed to 20% ammonium sulphide vapor in order to apply an ultra-thin CuS layer in order to get rid of surface states and create an ohmic contact with Au. The samples having a mask with 8×6 mm opening were exposed to the ammonium sulphide for 8 s by placing the samples 13 cm above the ammonium sulphide container.

## 2.5 Sputtering Au Contacts

As the final step of sample preparation, Au contacts were grown by sputtering at 10 mA current for 240 s by using 108 Cressington Sputter Coater.

# 3. RESULTS AND DISCUSSION

## 3.1 Current-Voltage Measurements

Fabricated devices were characterized by taking current-voltage measurements under illumination of 1.5 AM using Sciencetech SciSun 300 solar simulator. A mask having 4 mm<sup>2</sup> opening was applied on top of the illuminating surface in order to expose a known area of the device. Gamry series G 300 potentiostat/Galvanostat ZRA was used to obtain the measurements and a spring loaded gold probe was used as the contact to the device. As expected, V<sub>oc</sub> values higher than 400 mV were observed from most of the fabricated devices with J<sub>sc</sub> values around 8 mAcm<sup>-2</sup>. However, the current-voltage curves under dark and illumination for the best sample are shown in Fig. 1.

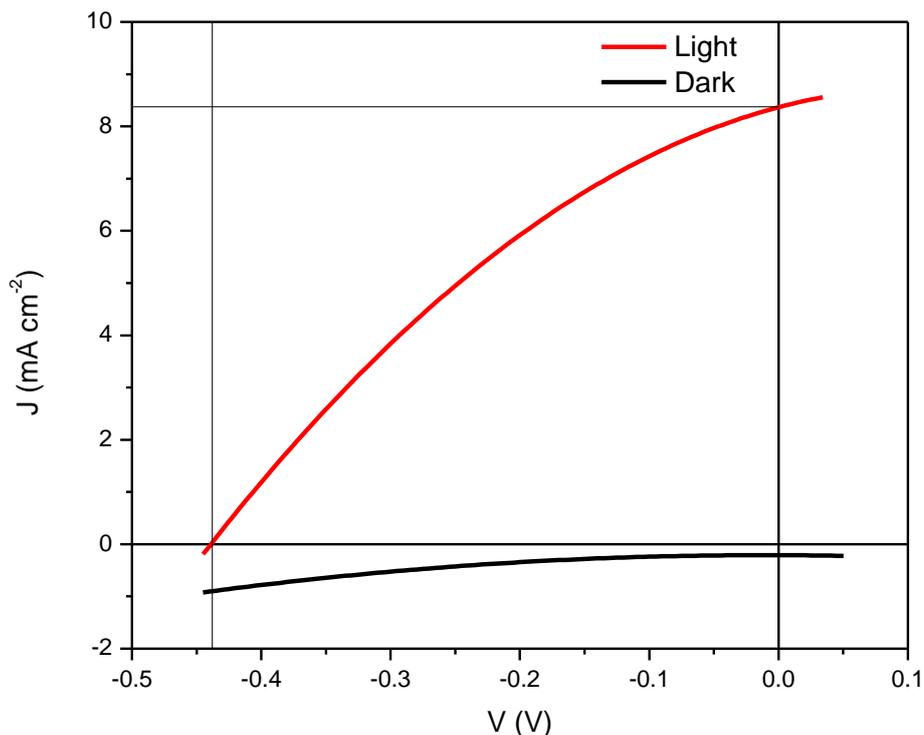


Figure 1. Dark and Light Current-Voltage measurements of Ti/n-Cu<sub>2</sub>O/ZnO/p-Cu<sub>2</sub>O/Au device under AM 1.5 illumination.

Device shown in Fig. 1 exhibited  $V_{oc}$  of 438 mV and  $J_{sc}$  of 8.37 mAcm<sup>-2</sup> with a FF of 34.9% resulting an efficiency ( $\eta$ ) of 1.28%. Although these results are low compared to the best device fabricated without introducing ZnO to the homojunction, these findings are encouraging because still significant photoresponse is produced by the device after introducing ZnO. The best Ti/n-Cu<sub>2</sub>O/p-Cu<sub>2</sub>O/Au device produced  $V_{oc}$  of 445 mV,  $J_{sc}$  of 12.95 mA cm<sup>-2</sup>, FF of 39.5% and  $\eta$  of 2.28%. When comparing the results of two devices, the value of  $J_{sc}$  reduced from 12.95 to 8.37 mAcm<sup>-2</sup>. In this present investigation, it was expected to improve the  $V_{oc}$ , FF and  $\eta$  values of the device with the introduction of ZnO buffer layer while preserving the resulted high  $J_{sc}$  value. In order to penetrate photogenerated elections from p-Cu<sub>2</sub>O to n-Cu<sub>2</sub>O and holes from n-Cu<sub>2</sub>O to p-Cu<sub>2</sub>O without trapping, the thickness of the ZnO layer is crucial and there should be few atomic layer thick layers. Therefore, the thickness of the ZnO layer has to be carefully controlled to achieve the goal.

### 3.2 Structural Characterization

Prepared samples were characterized by HEXRD measurements to confirm the growth of ZnO on Cu<sub>2</sub>O. Two samples of n-Cu<sub>2</sub>O and n-Cu<sub>2</sub>O/ZnO were prepared and Cu<sub>2</sub>O and Cu<sub>2</sub>O/ZnO layers were peeled off and put inside a capillary tube and scanned with high energy X-rays at wavelength of 0.49592 Angstrom. As shown in Fig. 2, curve (a) is the

XRD pattern of the n-Cu<sub>2</sub>O sample where the curve (b) represents the XRD pattern of the n-Cu<sub>2</sub>O/ZnO bi-layer. All the XRD peaks shown in curve (a) are corresponding reflections of n-Cu<sub>2</sub>O planes indicating the growth of single phase n-Cu<sub>2</sub>O. The XRD pattern of the curve (2) shows the existence of three peaks in addition to the Cu<sub>2</sub>O peaks. These three peaks are corresponding reflections of ZnO material confirming the successful growth of ZnO on n-Cu<sub>2</sub>O. Peaks corresponding to Cu<sub>2</sub>O are quite clearly visible in both samples however ZnO produces very low intensity peaks indicating the formation of a very thin ZnO layer compared to the Cu<sub>2</sub>O.

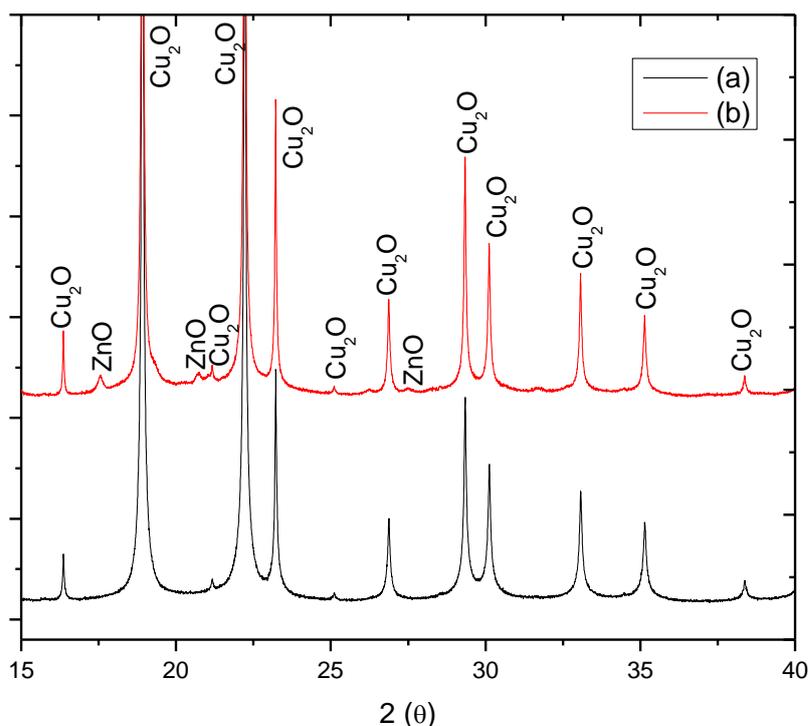


Figure 2. HEXRD measurements of (a) n-Cu<sub>2</sub>O annealed at 100 °C for 24 hours and (b) n-Cu<sub>2</sub>O/ ZnO annealed at 100 °C for 24 hours.

This preliminary investigation produced encouraging results on fabrication of Cu<sub>2</sub>O homojunction with the introduction of ZnO buffer layer in between two Cu<sub>2</sub>O layers. However, to achieve the goal, further investigations are required to improve the quality of the ZnO layer and optimization of thickness of the ZnO layer.

#### 4. CONCLUSION

In this study, possibility of fabrication of Cu<sub>2</sub>O homojunction with the introduction of ZnO buffer layer in between two Cu<sub>2</sub>O layers has been investigated and results revealed that it is possible to fabricate photoactive Cu<sub>2</sub>O homojunction with the deposition of ZnO buffer layer by spin coating technique. HEXRD characterizations confirmed the growth

of single phase ZnO on n-Cu<sub>2</sub>O. Best device produced V<sub>oc</sub> of 438 mV, J<sub>sc</sub> of 8.37 mAcm<sup>-2</sup>, FF of 34.9% and η of 1.28%. However, J<sub>sc</sub> value of the device reduced from 12.95 to 8.37 mAcm<sup>-2</sup> when compared to the Cu<sub>2</sub>O homojunction without ZnO buffer layer. Optimization of growth conditions and the thickness of the ZnO layer are required to improve the photoactive performance of the device.

## 5.ACKNOWLEDGEMENT

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## 5. REFERENCE

- [1] Jayathilaka, C, Kumara, L. S. R, Ohara, K, Song, C, Kohara, S, Sakata, O, Siripala, W, Jayanetti, S, *Enhancement of Solar Cell Performance of Electrodeposited Ti/n-Cu<sub>2</sub>O/p-Cu<sub>2</sub>O/Au Homojunction Solar Cells by Interface and Surface Modification*, Crystals, 10 (2020) 609 (14pp).
- [2] Wang, L, Tao, M, *Fabrication and characterization of p-n homojunctions in cuprous oxide by electrochemical deposition*, Electrochem. Solid-State Lett., 10 (2007) 248–250.
- [3] Kafi, F. S. B, Jayathileka, K. M. D. C, Wijesundera, R. P, Siripala, W, *Fermi-level pinning and effect of deposition bath pH on the flat-band potential of electrodeposited n-Cu<sub>2</sub>O in an aqueous electrolyte*, Phys. Status Solidi Basic Res., 253 (2016) 1965–1969.
- [4] Kalubowila, K. D. R. N, Gunawardhana, L. K. A. D. D. S, Wijesundera, R. P, Siripala, W, *Methods for improving n-type photoconductivity of electrodeposited Cu<sub>2</sub>O thin films*, Semicond. Sci. Technol., 29 (2014) 075012 (7pp).
- [5] Rakhshani, A. E, *Preparation, characteristics and photovoltaic properties of cuprous oxide-a review*, Solid State Electron., 29 (1986) 7–17.
- [6] Kotaro Mizuno, Masanobu Izaki, Kuniaki Murase, Tsutomu Shinagawa, Masaya Chigane, Minoru Inaba, Akimasa Tasaka, Yasuhiro Awakura, *Structural and Electrical Characterizations of Electrodeposited p-Type Semiconductor Cu<sub>2</sub>O Films*, J. Electrochem. Soc., 152, (2005) C179-C182, 2005,
- [7] Tingbin Yang, Wanzhu Cai, Donghuan Qin, Ergang Wang, Linfeng Lan, Xiong Gong, Junbiao Pen, Yong Cao, *Solution-processed zinc oxide thin film as a buffer layer for polymer solar cells with an inverted device structure*, J. Phys. Chem. C, 114 (2010) 6849–6853.
- [8] Stubhan, T, Oh, H, Pinna, L, Krantz, J, Litzov, I, Brabec, C. J, *Inverted organic solar cells using a solution processed aluminum-doped zinc oxide buffer layer*, Org. Electron., 12, (2011) 1539–1543.
- [9] Lv, P, Lin, L, Zheng, W, Zheng, M, Lai, F, *Photosensitivity of ZnO/Cu<sub>2</sub>O thin film heterojunction*, Optik (Stuttg.), 124 (2013) 2654–2657.

- [10] Illy, B. N, Cruickshank, A. C, Schumann, S, Campo, R. D, Jones, T. S, Heutz, S, McLachlan, M. A, McComb, D. W, Rileya, D. J, Ryan, M. P, *Electrodeposition of ZnO layers for photovoltaic applications: Controlling film thickness and orientation*, J. Mater. Chem., 21 (2011) 12949–12957.
- [11] Mahalingam, T, John, V. S, Raja, M, Su, Y. K, Sebastian, P. J, *Electrodeposition and characterization of transparent ZnO thin films*, Sol. Energy Mater. Sol. Cells, 88 (2005) 227–235.
- [12] Krunksn, M, Karber, E, Katerski, A, Otto, K, Acik, I. O, Dedova, T, Mere, A, *Extremely thin absorber layer solar cells on zinc oxide nanorods by chemical spray*, Sol. Energy Mater. Sol. Cells, 94 (2010) 1191–1195.
- [13] Dolzhenkov, V. N., Maltzagov, I. D, Makarova, A. I, Kamarova, S, Kukhtin, P. V, *Software Tools for Ontology Development*, International Journal of Advanced Trends in Computer Science and Engineering, 9 (2020) 935-941. Available from: <http://www.warse.org/IJATCSE/static/pdf/file/ijatcse05922020.pdf>
- [14] Raship, N. A, Sahdan, M. Z, Adriyanto, F, Nurfazliana, M. F, Bakri, A. S, *Effect of annealing temperature on the properties of copper oxide films prepared by dip coating technique*, AIP Conf. Proc., 1788 (2017) 03121 (7pp).
- [15] Kamalasanan, M. N, Chandra, S, *Sol-gel synthesis of ZnO thin films*, Thin Solid Films, 288 (1996) 112–115.